

High Purity Pfa Gas Washing Bottle Corrosion Resistant Gas Absorption Vessel With Ptfе Cap And Customizable Reaction Chamber

Item Number: PL-CP199



Introduction

Engineered for trace analysis, this high-purity PFA gas washing bottle offers exceptional chemical resistance and low metal leaching. Ideal for corrosive gas absorption and humidity regulation in critical laboratory environments where sample integrity is paramount for reproducible results.

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Application	Description	Key Benefit
Trace Element Analysis	Used as a reagent storage and gas scrubbing vessel for ICP-OES and ICP-MS workflows.	Minimizes metal ion contamination for sub-ppb detection limits.
Semiconductor Processing	Scrubbing and purification of high-purity gases used in wafer fabrication and etching.	Resists HF and other aggressive chemicals used in microelectronics.
Humidity Control	Generating precise humidity gradients for carrier gases in atmospheric chemistry research.	Produces more uniform and stable humidity than simple atomization.
Corrosive Gas Absorption	Capturing volatile acidic or basic gases during chemical synthesis or waste stream treatment.	Long-term durability in the presence of concentrated HCl, H ₂ SO ₄ , and NaOH.
Pharmaceutical Synthesis	Reaction vessel for specialized pharmaceutical intermediates requiring high purity.	Prevents organic solvent penetration and ensures active ingredient purity.
Environmental Monitoring	Collection and absorption of air pollutants and volatile organic compounds (VOCs) for analysis.	High recovery rates due to the non-stick, inert PFA surface.
Battery Testing	Gas management for electrochemical cells and battery electrolyte analysis.	Maintains integrity in the presence of reactive lithium salts and solvents.

Feature	Specification for Item PL-CP199
Model Number	PL-CP199
Primary Material	High-Purity PFA (Perfluoroalkoxy)
Cap Material	High-Density PTFE (Polytetrafluoroethylene)
Chemical Compatibility	Universal (Resistant to HF, Aqua Regia, Strong Bases, and Solvents)
Temperature Range	-200°C to +260°C
Leaching Profile	Extremely low metal ion and TOC leaching
Surface Tension	Low energy, hydrophobic, non-stick
Configuration	Gas Washing / Absorption / Reaction Chamber
Customization Options	Fully Customizable (Dimensions, Volume, Fittings, Tubing)

Application	Description	Key Benefit
Feature	Specification for Item PL-CP199	
Sealing Mechanism	Precision-threaded screw cap with integrated seals	
Manufacturing Process	CNC Machined and custom-fabricated to order	